



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Raaijmakers et al.
Appl. No. : 09/764,711
Filed : January 18, 2001
For : METHOD OF DEPOSITING
SILICON WITH HIGH STEP
COVERAGE
Examiner : Roman, A.
Group Art Unit : 2812

I hereby certify that this correspondence and all
marked attachments are being deposited with the
United States Postal Service as first class mail in
an envelope addressed to: Commissioner for
Patents, Washington, D.C. 20231, on

December 7, 2001

(Date)

Adeel S. Akhtar

Adeel S. Akhtar, Reg. No. 41,394

TRANSMITTAL LETTER

COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231
ATTENTION: APPLICATION BRANCH

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with two (2) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.

Adeel S. Akhtar

Adeel S. Akhtar
Registration No. 41,394
Attorney of Record

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